

Abatement of greenhouse gases using surface-wave microwave discharges sustained at atmospheric pressure

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Outline

- Introduction
- Abatement method
- Working example: abatement of SF_6 in N_2/O_2 gas mixture
- Conclusion

Introduction

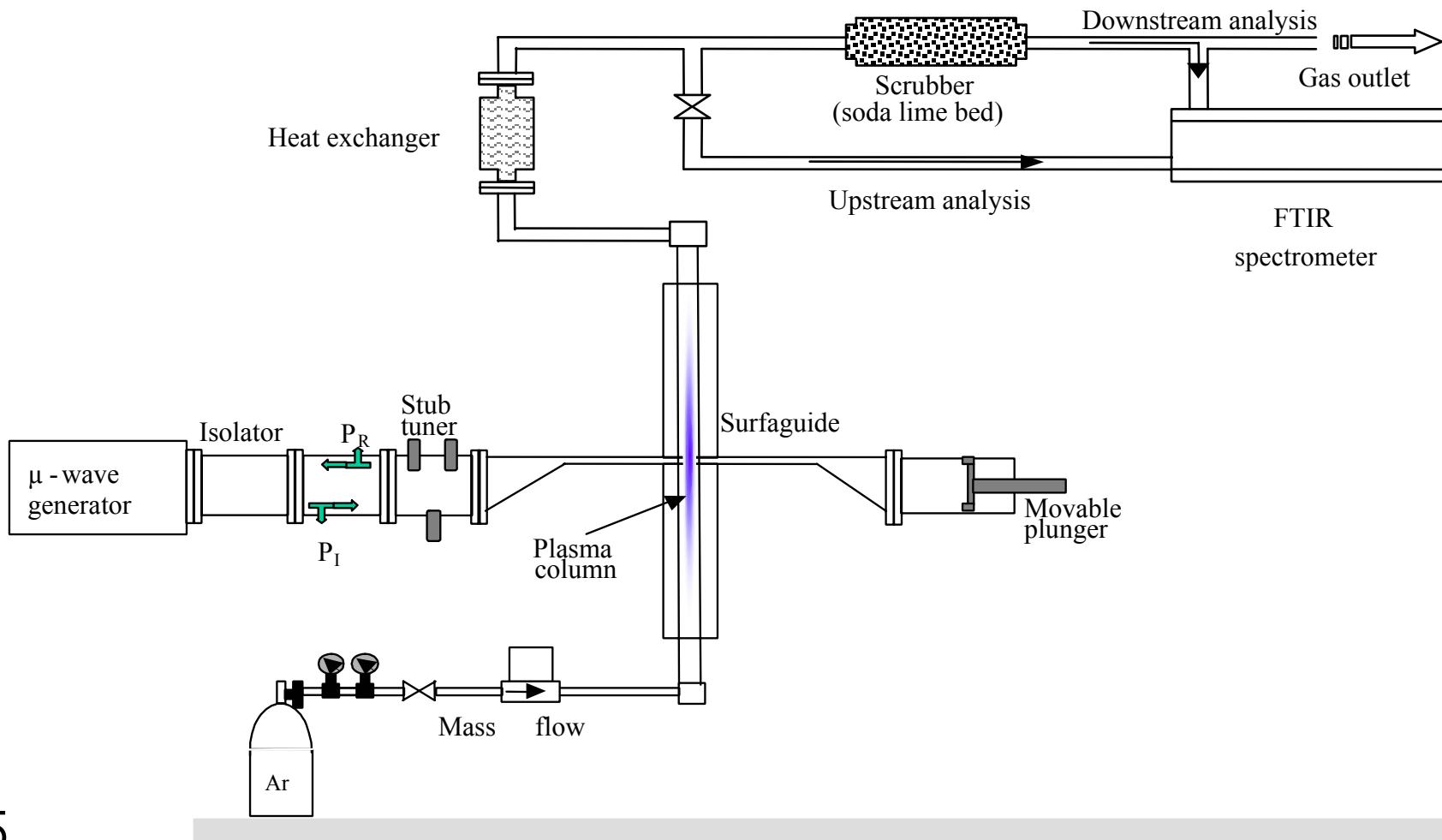
- Context of the work
 - ✓ Abatement of greenhouse gases
 - ✓ Destruction of CF_4 and SF_6 (diluted into N_2) from microelectronic fabs
- Conventional methods
 - ✓ Incineration : low conversion rates
 - ✓ Combustion : massive CH_4/H_2 feed flows
- Plasma solution
 - ✓ High destruction rate
 - ✓ Low energy consumption
 - ✓ Selective chemistry
 - ✓ Harmless byproducts

Abatement scheme

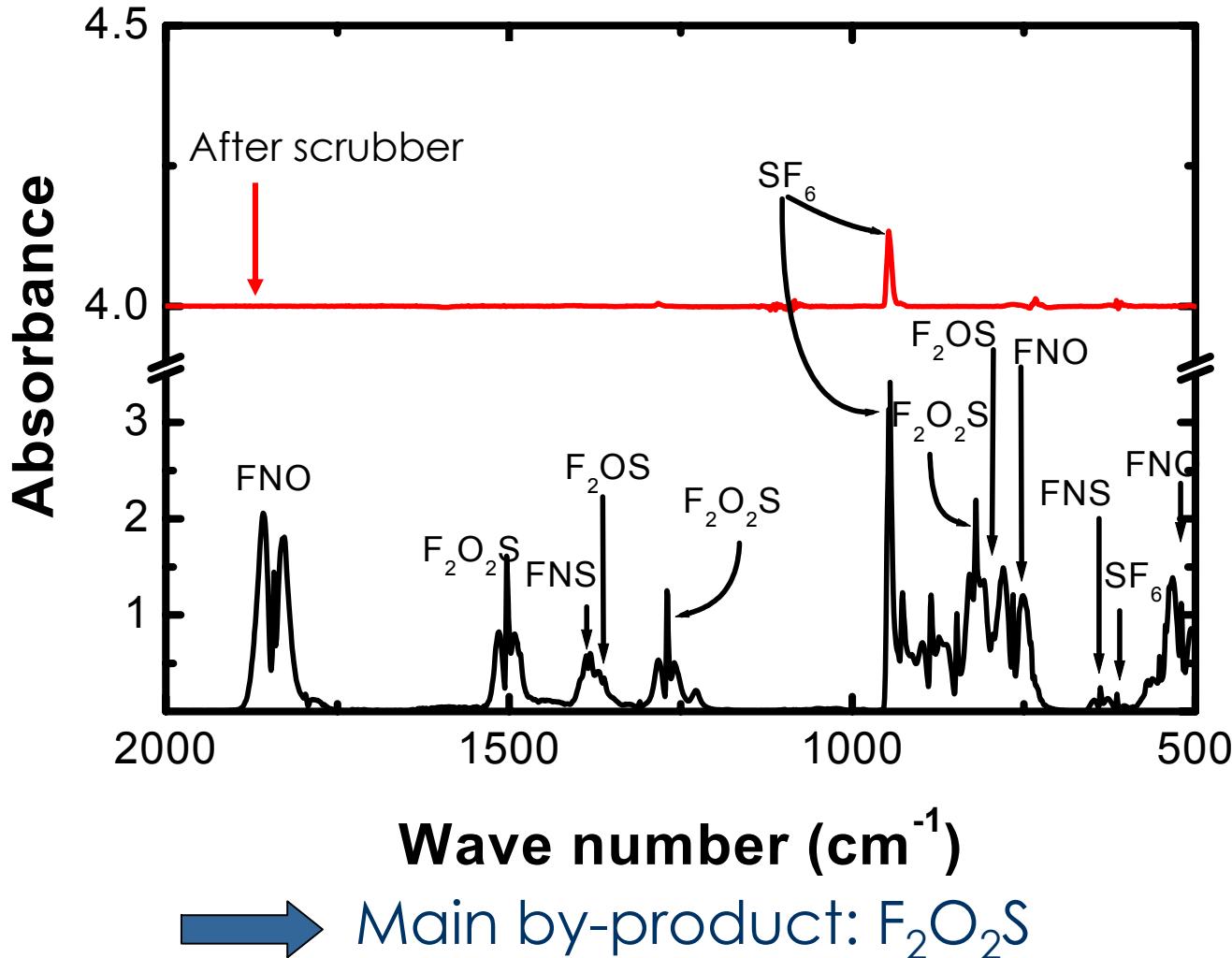
- Non equilibrium plasma :
 - ✓ $T_e \gg T_n \approx T_i$
 - ✓ Low enthalpy ($T_{\text{gas}} \sim 1000\text{-}5000 \text{ K}$, $T_e > 10,000 \text{ K}$)
 - A two-step process
 - ✓ electron collisions on PFC molecules and background gas molecules
 - ✓ interaction of molecular fragments and radicals with (added) oxygen atoms: $[\text{O}_2] \approx [\text{PFC}]$
 - Oxidation: elimination of PFC molecule
 - Non-oxidized by-products recombination: reformation of PFC molecule
- ⇒ Trapping of residues on a scrubber
- ✓ Humidified soda lime (alkaline bed)
 - ✓ No hazardous by-products at exhaust

Experimental arrangement

- 1- Surface-wave discharge (SWD) scheme : *Surfaguide*

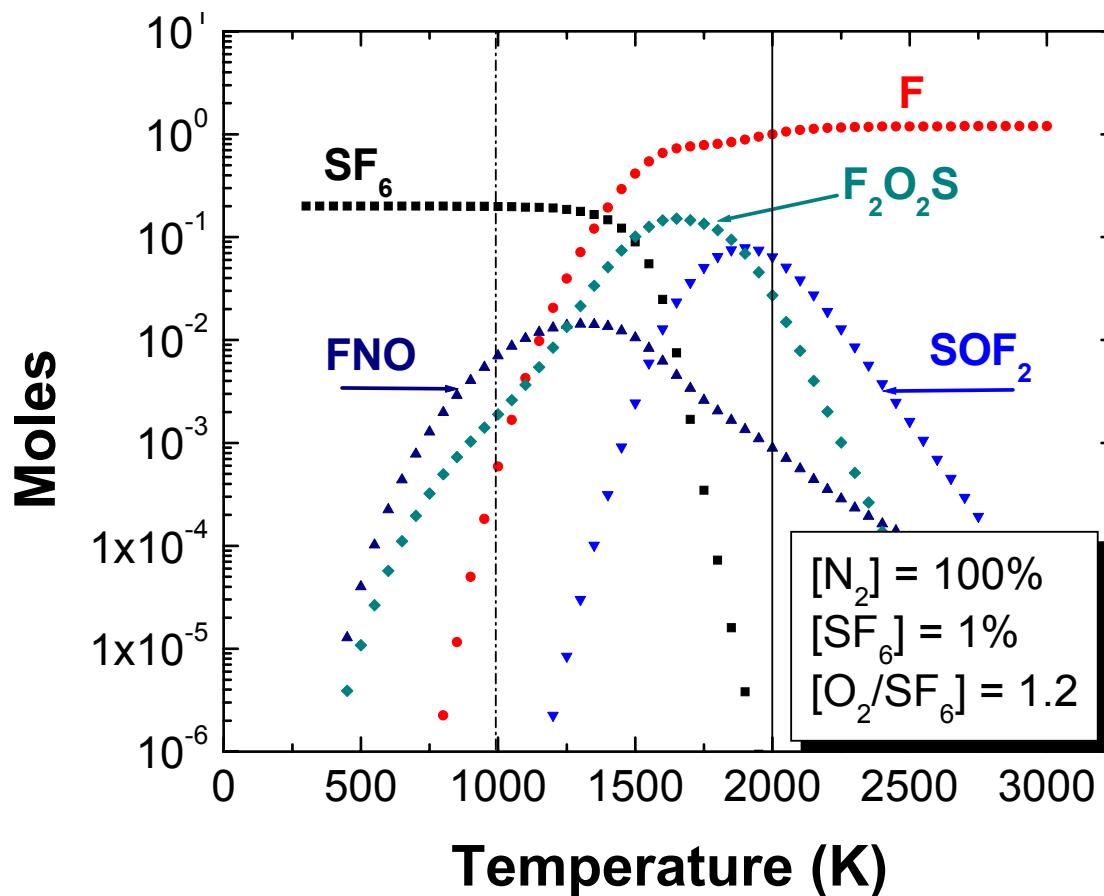


By-products analysis



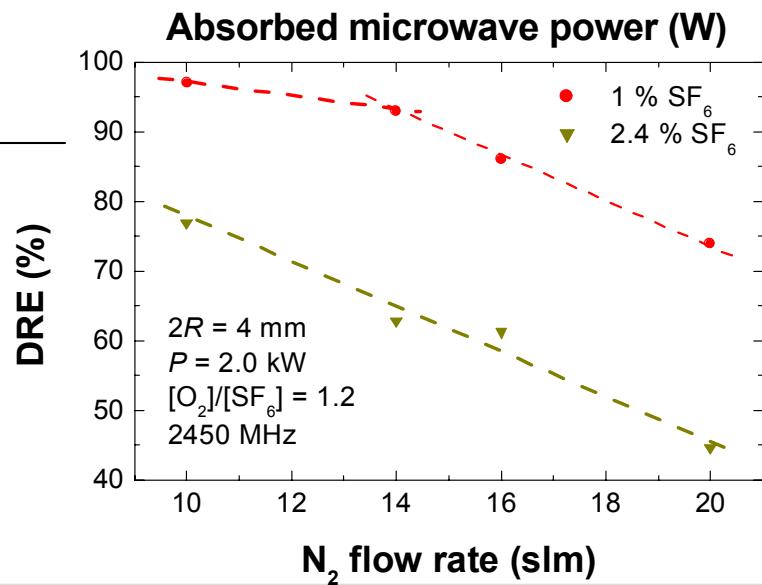
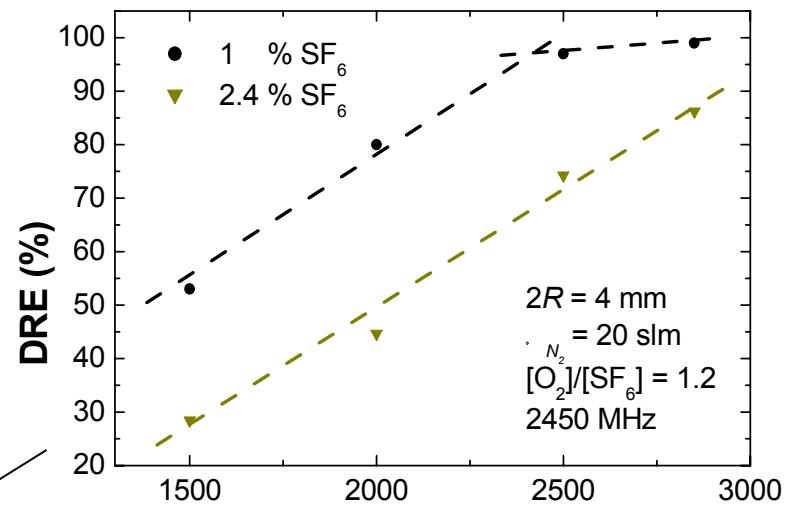
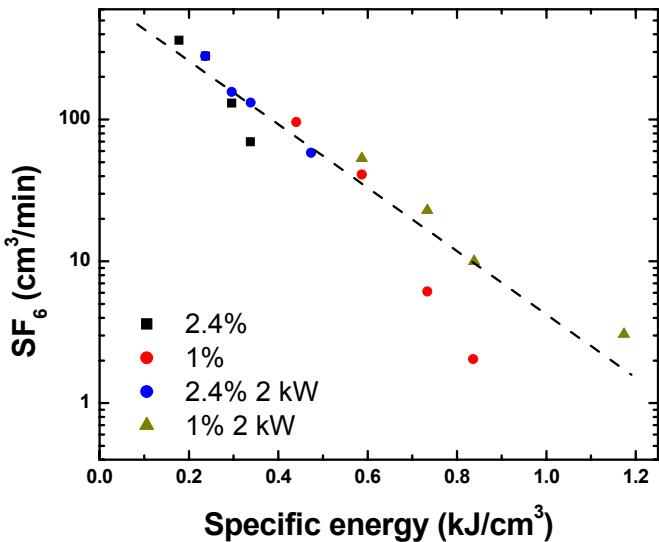
Equilibrium Calculation: SF₆-O₂-N₂

- Molar fraction of SF₆ by-products



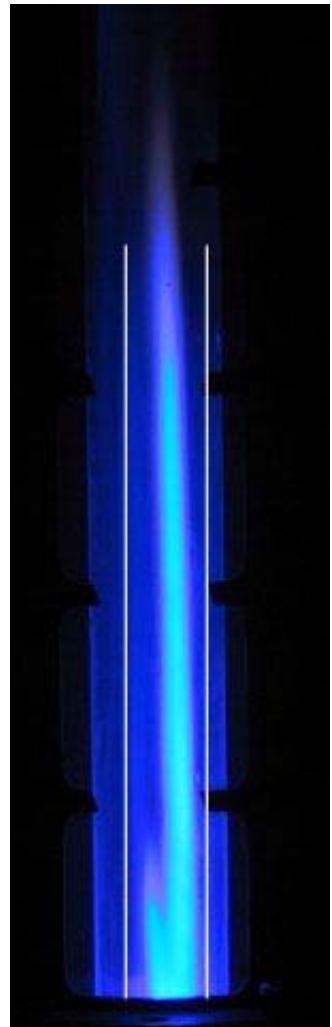
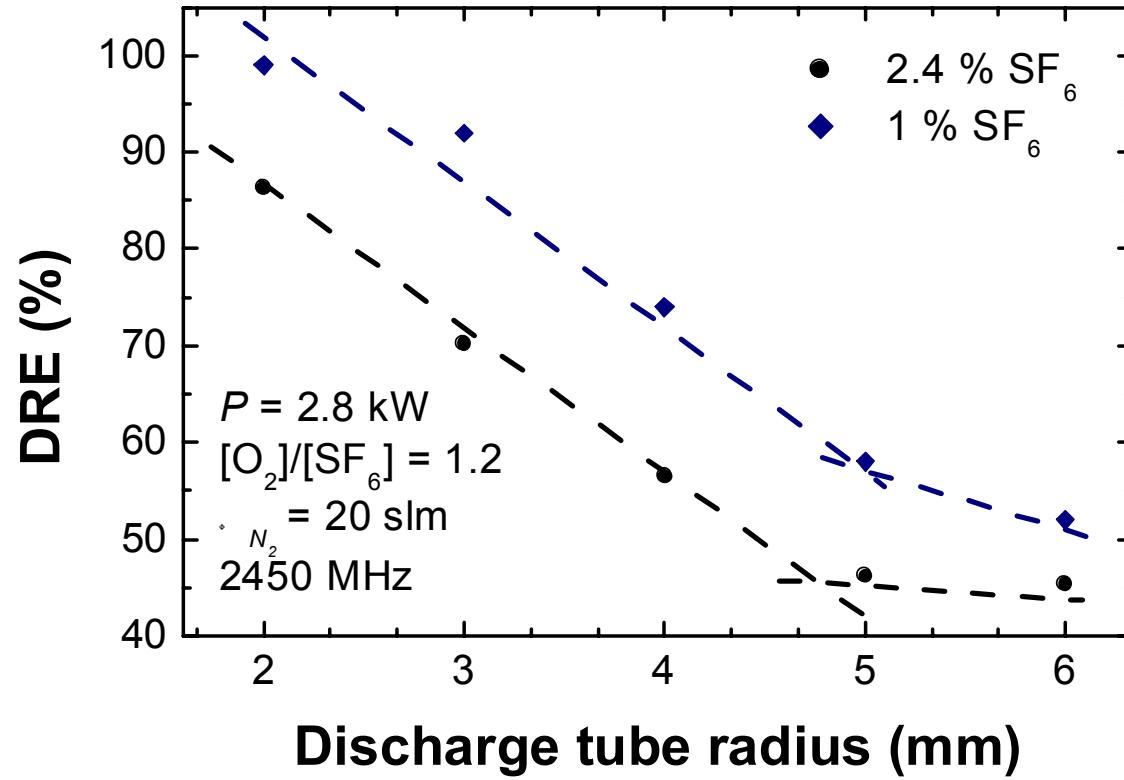
Abatement of SF₆: dissociation

- Influence of microwave power
- Influence of N₂ flow rate
 - ✓ Linear dependence of DRE vs. P
 - SWD property : $P=N \times \theta$
 - ✓ Second slope (1%) : SF₆ reformation



Abatement of SF₆

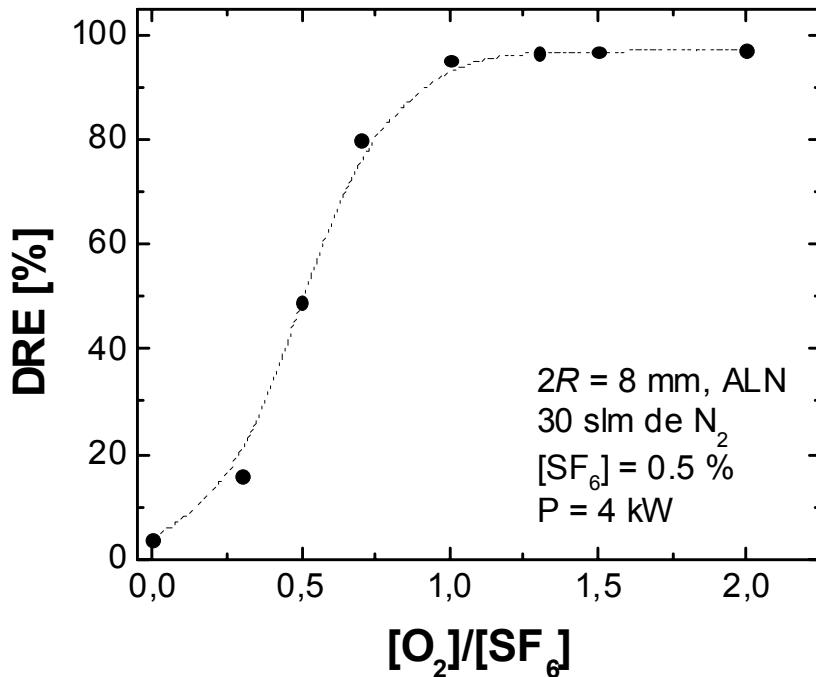
- Influence of radial contraction



→ Contraction sets up a limit for tube radius

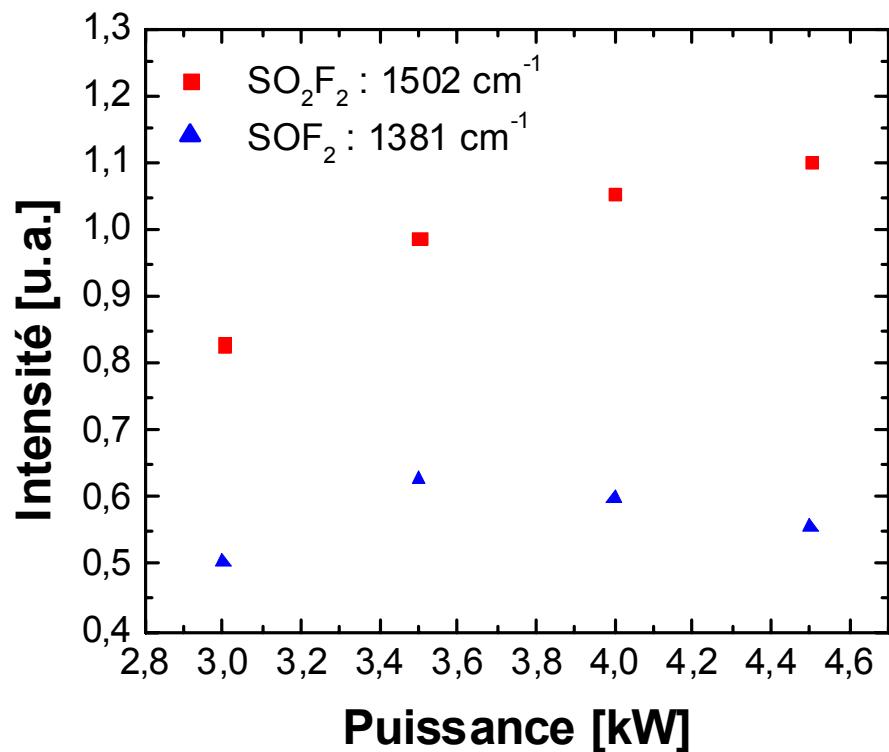
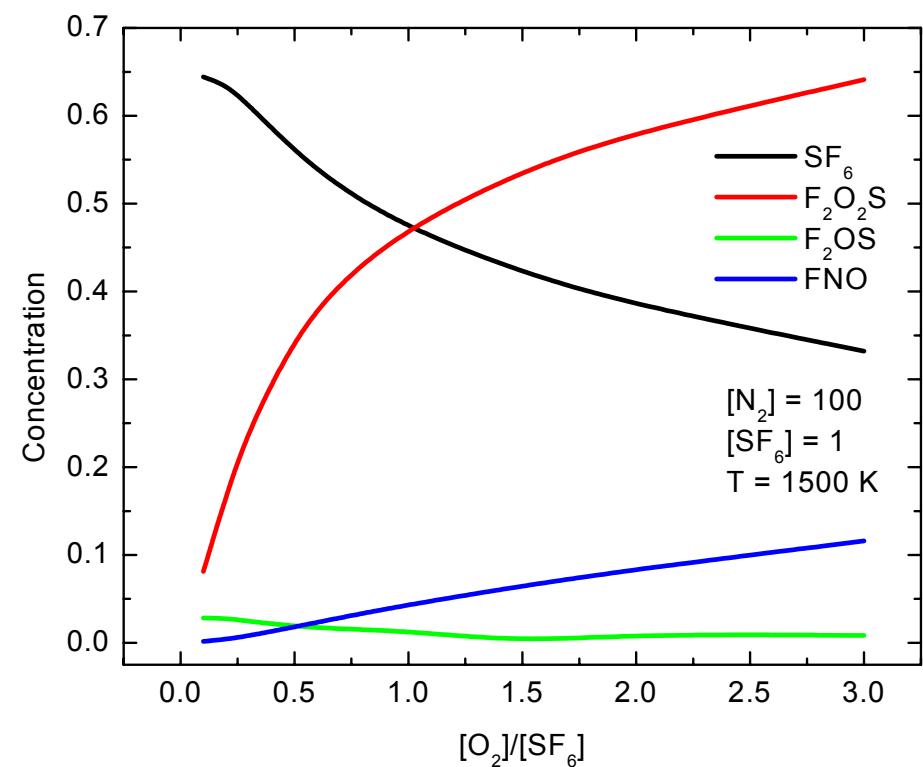
Abatement of SF₆ : oxidation

- Influence of the O₂/SF₆ ratio
- Oxidation vs. Reformation
 - ✓ [O₂]/[SF₆] < 1 : DRE determined by reformation rate
 - ✓ [O₂]/[SF₆] ≥ 1 : full oxidation
- Stoichiometric ratio 2:1 of O to S
 - ✓ Main by-product: F₂O₂S



Thermodynamic calculations: SF₆-N₂-O₂

- Influence of [O₂]/[SF₆] ratio



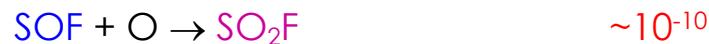
Gas-phase reactions

- ✓ Electron-impact dissociation

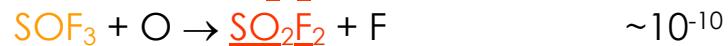


- ✓ Gas-phase reactions reaction rates (cm³/s)

Radical reactions



Abatement of SF₆



Reformation



Not observed with MW plasmas



Conclusion

- Abatement of PFCs in SWD at atmospheric pressure
 - ✓ Dissociation and fragmentation \Rightarrow increase with microwave power (electron density)
 - ✓ Reformation vs. oxidation \Rightarrow gas temperature
- ☞ DRE increases with increasing specific energy
- Modeling: by-products composition at plasma exhaust adequately described by equilibrium calculations
- Limiting factors
 - ✓ PFCs reformation
 - ✓ Contraction and filamentation of SWDs (limit for discharge tube radius)

Industrial application: UPAS (Air Liquide)

